

Annular microelectromechanical angular rate sensor**ABSTRACT**

The invention relates to a microelectromechanical angular rate sensor (100) having a flexible ring structure (110) which forms a circle in an idle state and which is suitable for producing an excitation oscillation substantially parallel to the plane of the circle above a substrate, said excitation oscillation being superimposed with a detection oscillation produced by a Coriolis force during a rotation of the ring structure (110). The microelectromechanical angular rate sensor also has at least one coupling structure (120) which is connected to the ring structure (110) and is designed so as to be suitable for compensating for a quadrature error of the angular rate sensor (100) together with electrodes (130) which are fixed to the substrate.

(Fig. 3)